

E M Optomechanical Announces New Low-Cost 3D MEMS Profiler for under \$20K

E M Optomechanical, Inc., also known as EMOpto, has developed a new low-cost version of its OPTOPro™ line of 3D MEMS Optical Profilers for use in testing and characterizing micro-electro-mechanical systems devices.

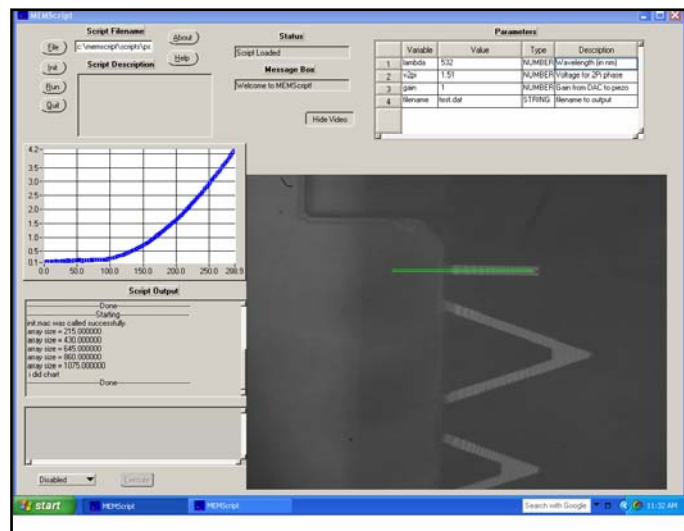
Gilbert, Arizona, January 20, 2011 - - E M Optomechanical, Inc., (EMOpto), recently introduced the latest in its line of Dynamic 3D MEMS Optical Profilers, known as the OPTOPro™ Model 622-Xe. The Profiler, based on exclusively licensed patented long-working distance interference microscopy technology, is being offered for under \$20K.

"Feedback from potential customers indicates that tight budgets are preventing them from purchasing our higher priced models and that \$20K would be a good price point for an entry level system," says Tom Swann, president of EMOpto. In addition to the Model 622-Xe, customers will have to provide a vibration isolation table, a structure to hold the profiler instrument and a means of holding and positioning the sample to be tested. "We have found that many prospective customers already have these capabilities available in-house," says Swann.

In addition to requiring the customer to furnish some of the system's components, the low price was achieved by redesigning the mechanical portion of the profiler instrument and trimming the margin on software. "Even at its low price, the Model 622-Xe is a valuable and versatile research tool and it can accommodate a wide range of upgrades" says Swann.

EMOpto's first generation line of products is intended primarily for use by micro-systems researchers for making real-time dynamic measurements of the micro- and nano-scale motions of micro-electro-mechanical systems (MEMS) devices and other micro-systems.

The technology behind EMOpto's line of products was initially developed because there were no commercial optical profilers tailored specifically to the needs of micro-systems researchers. Its key feature is that it allows a long working distance without any sacrifice in measurement resolution. This allows capabilities not possible with other techniques such as allowing space for probes that are needed to attach to micro-system devices and viewing through portholes into vacuum chambers or through device cover glasses.



The profiler instrument is controlled by EMOpto's MEMScript™ Software that also acquires and analyzes the data collected. This software has several unique features, such as the ability to control micro-system devices, which by nature have moving parts, and making real time measurements of performance.

About E M Optomechanical, Inc.

E M Optomechanical, Inc. was spun-off from Optomec, Inc. in 1998 to provide opto-mechanical engineering, design and fabrication services to the photonics industry. The Company has transitioned to a product oriented Company committed to commercialization of exclusively licensed patented long-working distance interference microscope technology for micro-systems research and development.

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